

REMARKS

Claims 1-20 are pending in this application. Selected claims are amended to more clearly define the invention and are not needed to overcome the prior art rejections.

Claim Rejection under 35 USC 112

Claims 1-20 are rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the written description requirement. Claims 1, 10 and 14, along with other claims are amended to include language that was originally disclosed in the specification at least on page 22. In view of the claim amendments, the Examiner is respectfully requested to withdraw this rejection.

Claims 1-30 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite. Claims 1, 10, 14, 20, 21 and 25 are amended to clarify the invention by including language that was originally disclosed in the specification at least on page 22. In view of the claim amendments, the Examiner is respectfully requested to withdraw this rejection.

Claim Rejections under 35 USC 102

Claims 1-3, 6-17, 19, 20, and 25-30 are rejected under 35 U.S.C. 102(b) as being anticipated by Fujimoto (6,245,585). Applicants respectfully traverse this rejection.

Independent claims 1, 10, 14, 20 and 25 recite, among other things, a substrate table configured to move the substrate along at least one path that is substantially parallel to a direction of a local tangent on an edge contour of the substrate. According to one embodiment of the invention, since the direction of the straight lines are substantially parallel to the direction of local tangents on the edge contour, and thus may be at an angle with respect to the exposure direction y, the measurement areas are much closer to the edge exclusion zone (see the specification at page 22, paragraph 0085).

By contrast, Fujimoto discloses an actuator 124 that horizontally moves the base member 111 stepwise by a distance corresponding to one cell in the X and Y directions to set the wafer 109 in a desired cell position on the X-Y plane (see Fujimoto, col. 4, lines 29-33 and Fig 4a). However, Fujimoto fails to teach or suggest a substrate table configured to move the substrate along at least one path that is substantially parallel to a direction of a local tangent on an edge contour of the substrate. As a result, the claimed invention is distinguished from Fujimoto.

Since Fujimoto neither discloses nor suggests the invention claimed in independent claim 1 and its dependent claims 2, 3, 6-9, or the invention claimed in independent claim 10 and its dependent claims 11-13, or the invention claimed in independent claim 14 and its

dependent claims 15-17 and 19, or the invention claimed in independent claim 20, or the invention claimed in independent claim 25 and its dependent claims 26-30, these claims clearly are not anticipated by the disclosure of Fujimoto. For the foregoing reasons, reconsideration and allowance of these claims are requested.

Claims 1-20 and 25-30 are rejected under 35 U.S.C. 102(a) as being anticipated by Wakamoto (2003/0058423). Applicants respectfully traverse this rejection.

Independent claims 1, 10, 14, 20 and 25 recite, among other things, a substrate table configured to move the substrate along at least one path that is substantially parallel to a direction of a local tangent on an edge contour of the substrate. According to one embodiment of the invention, since the direction of the straight lines are substantially parallel to the direction of local tangents on the edge contour, and thus may be at an angle with respect to the exposure direction *y*, the measurement areas are much closer to the edge exclusion zone (see the specification at page 22, paragraph 0085).

By contrast, Wakamoto discloses that the slit-like illumination area 12W formed on the surface of wafer 14 moves relatively along the surface of the wafer 14 *along the scanning direction Y* (see Wakamoto at page 6, paragraph 0085 and Figs. 4a-7c). However, Wakamoto fails to teach or suggest a substrate table configured to move the substrate along at least one path that is substantially parallel to a direction of a local tangent on an edge contour of the substrate. As a result, the claimed invention is distinguished from Wakamoto.

Since Wakamoto neither discloses nor suggests the invention claimed in independent claim 1 and its dependent claims 2-9, or the invention claimed in independent claim 10 and its dependent claims 11-13, or the invention claimed in independent claim 14 and its dependent claims 15-19, or the invention claimed in independent claim 20, or the invention claimed in independent claim 25 and its dependent claims 26-30, these claims clearly are not anticipated by the disclosure of Wakamoto. For the foregoing reasons, reconsideration and allowance of these claims are requested.

Claim Rejections under 35 USC 103

Claims 21-24 are rejected under 35 U.S.C. 103(a) as being obvious over Fujimoto in view of Saka et al. (6,798,529). Applicants respectfully traverse this rejection.

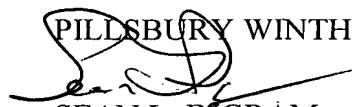
Independent claim 21 recites, among other things, a substrate table configured to move the substrate along at least two paths that are substantially parallel to a direction of a local tangent on an edge contour of said substrate. According to one embodiment of the invention, since the direction of the straight lines are substantially parallel to the direction of local tangents on the edge contour, and thus may be at an angle with respect to the exposure direction y, the measurement areas are much closer to the edge exclusion zone (see the specification at page 22, paragraph 0085).

As discussed above, Fujimoto fails to teach or suggest this feature. Saka et al. is directed to a system and method for providing in-situ monitoring of the removal of materials in localized regions of a semiconductor wafer or substrate during chemical mechanical polishing (CMP) (see Saka et al., the Abstract). The Examiner alleges that "Saka discloses the substrate moving substantially parallel to a direction of a local tangent to a part of an edge contour in Fig. 17 and col. 19, lines 13-40" (see page 5 of the October 28, 2005 office action). This portion of Saka et al. discloses taking data from within adjacent dies at the same radius, and fails to teach or suggest *a substrate table configured to move the substrate* along at least two paths that are substantially parallel to a direction of a local tangent on an edge contour of said substrate. Thus, Fujimoto and Saka et al. remain deficient, both alone and in combination.

In view of the foregoing comments, Applicants respectfully submit that the Examiner has failed to establish a case of obviousness based on Fujimoto in view of Saka et al. Thus, claim 21 is allowable and claims 22-24 are allowable at least by virtue of their dependency.

Please charge any fees associated with the submission of this paper to Deposit Account Number 033975. The Commissioner for Patents is also authorized to credit any over payments to the above-referenced Deposit Account.

Respectfully submitted,



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